

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10007054	FILING DATE 12/03/2001	CLASS 28118	SUBCLASS 410522	GAU 2811	1763 EXAMINER W. Fahmy
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*CONTINUING DATA VERIFIED:

** FOREIGN APPLICATIONS VERIFIED:

JAPAN 2001-119711 04/18/2001

JAPAN 2001-245172 08/13/2001

PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☐ yes ☐ no

35 USC 119 conditions met ☐ yes ☐ no

Verified and Acknowledged Examiners's initials

ATTORNEY DOCKET NO

FUSO3.001AUS

TITLE : Wafer oxidation reactor and a method for forming a semiconductor device

U.S. DEPT. OF COM. PAT. & TM. PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drawn	Figs. Drawn
			Print Fig.
<input type="checkbox"/> TERMINAL DISCLAIMER		Primary Examiner	
		PREPARED FOR ISSUE	
		Application Examiner	
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